

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of	:	Customer Number: 53080
	:	
Akio MISAKA	:	Confirmation Number: 7423
	:	
Application No.: 10/576,120	:	Group Art Unit: 1795
	:	
Filed: April 18, 2006	:	Examiner: RASHID A. ALAM
	:	
For:		PHOTOMASK AND PATTERN FORMATION METHOD AND MASK DATA GENERATION METHOD USING THE SAME

CORRECTED INFORMATION DISCLOSURE STATEMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

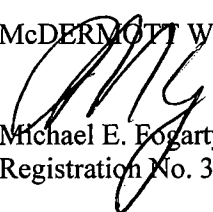
Dear Sir:

This Corrected Information Disclosure Statement is being filed after the submission of the Information Disclosure Statement on April 18, 2006. Please note that the first US Patent Document Applicant was listed incorrectly as Muehlhaeuser. The US Patent Document Applicant should be listed as Misaka. A corrected PTO Form-1449 is filed herewith.

Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

McDERMOTT WILL & EMERY LLP


Michael E. Fogarty
Registration No. 36,139

600 13th Street, N.W.
Washington, DC 20005-3096
Phone: 202.756.8000 MEF:mjb
Facsimile: 202.756.8087
Date: February 10, 2009

**Please recognize our Customer No. 53080 as
our correspondence address.**